

New Device Physics of Cross-Gap Electroluminescence in Unipolar-Doped InGaAs/AlAs RTDs

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Double barrier resonant tunneling diodes (DBRTDs) exhibit a characteristic negative differential resistance (NDR), which allows for high-speed oscillation and switching; e.g. In_{0.53}Ga_{0.47}As/AlAs DBRTDs for high-speed oscillation applications [1, 2]. Recently, a cross-gap electroluminescence (EL) phenomenon from InGaAs DBRTDs at room temperature was discovered despite the absence of p-doped layers [3]. This unipolar-doped EL had not been previously reported in the past 40+ years of RTD history. The indispensable holes for the light emission are thought to be produced by interband tunneling through the narrow bandgap of In_{0.53}Ga_{0.47}As, which is illustrated in Fig. 1. The radiative recombination is thought to occur primarily in the In_{0.53}Ga_{0.47}As emitter region, and thus the emission spectrum is near the bandgap of In_{0.53}Ga_{0.47}As (~1650 nm at 295 K). The EL property combined with high-speed modulation can be utilized for future high-speed optical clocking applications. In this abstract we report a more detailed characterization of unipolar-doped In_{0.53}Ga_{0.47}As/AlAs DBRTDs to gain a better understanding of the new EL phenomenon.

The heterostructure was grown by molecular beam epitaxy (MBE) on a semi-insulating InP substrate. The heterostructure stack has a 4.4 nm thick unintentionally doped (UID) In_{0.53}Ga_{0.47}As quantum well and 2.4 nm UID AlAs barriers on either side [Fig. 2 (a)]. The device shown in Fig. 2 (b) was fabricated using four mask levels. The first mask level defined a 15 μ m mesa. The mesas were etched, using inductively coupled plasma reactive ion etching (ICP-RIE) with a BCl₃ gas mixture, down to the highly doped In_{0.53}Ga_{0.47}As bottom contact layer in the collector region. The second mask layer was used to isolate the individual devices. A conformal passivating SiO₂ layer was then deposited using plasma enhanced chemical vapor deposition (PECVD). Contact vias were defined and etched with a CF₄ gas mixture using ICP-RIE through the SiO₂ layer with the third mask. The last mask was utilized to deposit the contact pads. The annular top (5 μ m aperture) contact design allowed for more light to escape from the surface.

The characterizations entailed the following measurements: (1) current-voltage (I-V); (2) light emission intensity versus bias voltage (L-V); (3) EL spectrum; (4) shot noise; and (5) EL temperature dependence. Fig. 3 shows the measured I-V and the L-V curves at T \approx 300 K. The onset of NDR is at 2.2 V with a peak-to-valley ratio of \sim 8.3. The EL has a threshold at a lower voltage (\sim 1.25 V). Fig. 4 shows both the full shot noise and the total RTD noise power spectral density of the In_{0.53}Ga_{0.47}As/AlAs DBRTD device at T \approx 300K. The low shot noise at biases $>$ 3V into the second positive differential resistance (PDR) region supports our thesis that the holes for the light emission are produced by interband tunneling, not impact ionization [4]. Fig. 5 shows an overlay plot of the normalized EL spectra of an RTD biased at 3.5 V with peaks marked and the theoretically modeled bandgap of In_{0.53}Ga_{0.47}As at various temperatures. The consistency between the theoretical model and measured bandgap corresponding to the spectra peak further supports the theory that describes the light emission as being cross-gap, radiative recombination in the InGaAs emitter [Fig. 5, Fig. 1]. The decreasing trend in full width at half maxima (FWHM) with a decrease in temperature could be due to a reduction in phonon scattering [Fig. 6] [5]. The preliminary external quantum efficiency (EQE) measurements resulted in an EQE of \sim 0.44% for unipolar-doped In_{0.53}Ga_{0.47}As/AlAs DBRTDs. Balancing the electron resonant and interband tunneling currents via tunneling engineering can result in substantially improved EQEs.

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References: [1] T. Broekaert et al, *Appl. Phys. Lett.* **53**, 1545 (1988). [2] T. Inata et al, *Japanese Journal of Applied Physics* **26**, L1332-L1334 (1987). [3] E. R. Brown et al, <https://arxiv.org/abs/1804.07666>. [4] E. R. Brown et al, <https://arxiv.org/abs/1806.09270>. [5] W. Z. Shen et al, *National Lab. of Infrared Phys.* **65**, 2728 (1994). [6] E. Zielinski et al, *J. Appl. Phys.* **59**, 2196 (1986).

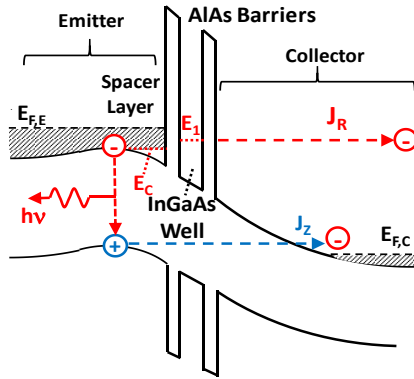
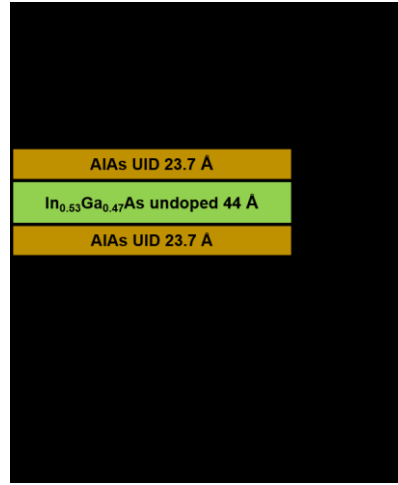
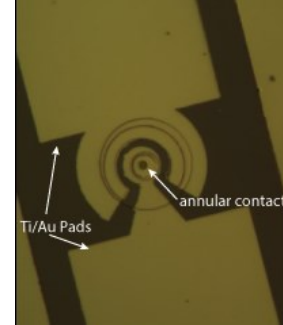


Fig. 1. The illustration of unipolar-doped light emission in InGaAs/AIAs DBRTDs.



(a)



(b)

Fig. 2. (a) The heterostructure stack (b) Top-view image of the device.

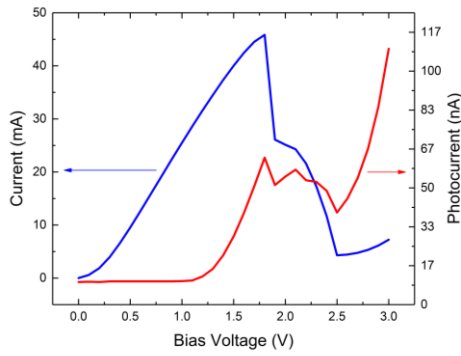


Fig. 3. I-V curve and L-V curve at $T \approx 300$ K.

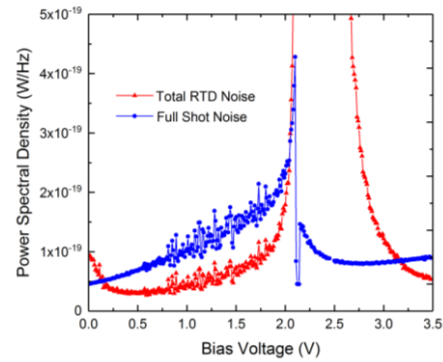


Fig. 4. Power spectral density of full shot noise and total RTD noise.

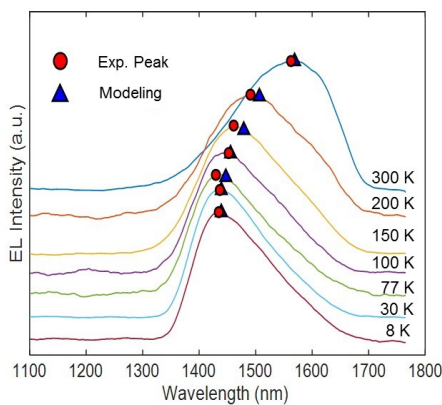


Fig. 5. (a) EL spectrum at a bias of 3.5V and theoretical modeling [6] of $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$ bandgap at different temperatures. The plots have been shifted vertically for clarity.

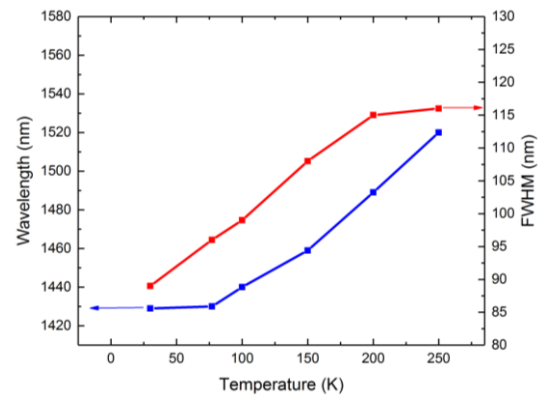


Fig. 6. Peak spectral wavelength and FWHM of EL spectra vs. temperature.